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## BIB DATA SHEET

CONFIRMATION NO. 9288

SERIAL NUMBER	FILING or 371(c) DATE	CLASS	GROUP ART UNIT	ATTORNEY DOCKET NO.		
10/594,458	09/26/2006 RULE	438	1792	129546		
<b>APPLICANTS</b> Hideki Sato, Gunma, JAPAN; <b>** CONTINUING DATA *****</b> This application is a 371 of PCT/JP05/04294 03/11/2005 <b>** FOREIGN APPLICATIONS *****</b> JAPAN 2004-095864 03/29/2004 <b>** IF REQUIRED, FOREIGN FILING LICENSE GRANTED **</b> 05/25/2007						
Foreign Priority claimed <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No 35 USC 119(a-d) conditions met <input type="checkbox"/> Yes <input checked="" type="checkbox"/> No Verified and Acknowledged <u>/LAN VINH/</u> <u>Examiner's Signature</u>		<input type="checkbox"/> Met after Allowance LV Initials	<b>STATE OR COUNTRY</b> JAPAN	<b>SHEETS DRAWINGS</b> 3	<b>TOTAL CLAIMS</b> 8	<b>INDEPENDENT CLAIMS</b> 1
<b>ADDRESS</b> OLIFF & BERRIDGE, PLC P.O. BOX 320850 ALEXANDRIA, VA 22320-4850 UNITED STATES						
<b>TITLE</b> Method For Evaluating Crystal Defects Of Silicon Wafer						
<b>FILING FEE RECEIVED</b> 900	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:			<input type="checkbox"/> All Fees		
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